

2004  
OFFICIAL

Attorney Docket No. UMC-96-279 CON  
Client Matter No. 81848.0016.001

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Serial No. 09/546,174	Confirmation No.: 4793
Application of: LIU, Chih-Chien et al	Customer No.: 25235
Filed: April 11, 2000	
Art Unit: 1711	
Examiner: SERGENT, R.A.	
Attorney Docket No. UMC-98-279 CON	
For: HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION PROCESS	

**AMENDMENT AND RESPONSE TO THE OFFICE ACTION**  
**MAILED DECEMBER 23, 2003**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:  
An Office Action was mailed in the above case December 23, 2003.  
Please reconsider the case in light of the amendment and remarks that follow.

**Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.**

Remarks begin on page 9 of this paper.

PAGE 318 \* RCVD AT 10/20/2014 4:42:34 PM (Eastern Standard Time) \* SVR-USPTO-EFXRF-12 \* DWS-8723086 \* CSD-\* DURATION (mm:ss) 04:38

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